



IFC

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application No. : 10/532,991 Confirmation No. : 2959

First Named Inventor : Mitsuhiro YUASA

Filed : April 28, 2005

TC/A.U. : 2812

Examiner : A. Roman

Docket No. : 101249.56268US

Customer No. : 23911

Title : Process Monitor and System for Producing Semiconductor

**REPLY**

**Mail Stop AMENDMENT**

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

Sir:

The following amendments and remarks are respectfully submitted in response to the *Ex parte Quayle* Office Action dated May 3, 2007.

**Amendments to the Claims** are reflected in the listing of claims which begins on page 2 of this paper.

**Remarks** begin on page 5 of this paper.